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Parf.?



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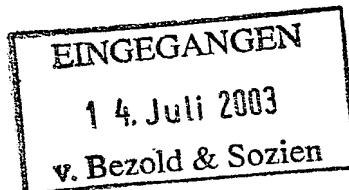
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Zeichen/Ref./Réf. 15831/EP Hz/hr	Anmeldung Nr./Application No./Demande n°./Patent Nr. /Patent No./Brevet n°. 02020889.8-2208-
Anmelder/Applicant/Demandeur/Patentinhaber/Proprietor/Titulaire Staib Instrumente GmbH	

COMMUNICATION

The European Patent Office herewith transmits as an enclosure the European search report for the above-mentioned European patent application.

If applicable, copies of the documents cited in the European search report are attached.

Additional set(s) of copies of the documents cited in the European search report is (are) enclosed as well.

The following specifications given by the applicant have been approved by the Search Division:

abstract

title

The abstract was modified by the Search Division and the definitive text is attached to this communication.

The following figure will be published together with the abstract:

1



REFUND OF THE SEARCH FEE

If applicable under Article 10 Rules relating to fees, a separate communication from the Receiving Section on the refund of the search fee will be sent later.

**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

EP 02 02 0889

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report. The members are as contained in the European Patent Office EDP file on. The European Patent Office is in no way liable for these particulars which are merely given for the purpose of information.

07-07-2003

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Y	* abstract; figures *	1	
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A	* paragraph '0044! - paragraph '0081!; figure 1 *	3,5,6, 11,12, 16,18	
D,A	RIJNDERS G J H ET AL: "IN SITU MONITORING DURING PULSED LASER DEPOSITION OF COMPLEX OXIDESUSING REFLECTION HIGH ENERGY ELECTRON DIFFRACTION UNDER HIGH OXYGENPRESSURE" APPLIED PHYSICS LETTERS, AMERICAN INSTITUTE OF PHYSICS. NEW YORK, US, vol. 70, no. 14, 7 April 1997 (1997-04-07), pages 1888-1890, XP000689523 ISSN: 0003-6951 * the whole document *	1,14	
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			H01J
The present search report has been drawn up for all claims			
1	Place of search THE HAGUE	Date of completion of the search 7 July 2003	Examiner Schaub, G
CATEGORY OF CITED DOCUMENTS			
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document	